

Title

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Abstract—Abstract

Index Terms—Keyword1, Keyword2

I. INTRODUCTION AND MOTIVATION

See [1].

A. Related work

Text

B. Contribution of this work

Text

II. FUNDAMENTALS AND IMPLEMENTATION

Text

III. TEST RESULTS, EVALUATION, AND DISCUSSION

Text

IV. CONCLUSION AND OUTLOOK

Text

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REFERENCES

- [1] T. Schlosser, M. Friedrich, F. Beuth, and D. Kowerko, “Improving automated visual fault inspection for semiconductor manufacturing using a hybrid multistage system of deep neural networks,” *Journal of Intelligent Manufacturing*, vol. 33, no. 4, pp. 1099–1123, 2022.